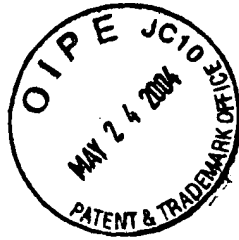


10/634,362



**PATENT**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of:  
Eugene P. Marsh

Serial No.: 10/634,362

Filed: August 8, 2003

For: **ATOMIC LAYER DEPOSITION OF  
METAL DURING THE FORMATION OF A  
SEMICONDUCTOR DEVICE**

§  
§ Group Art Unit: 2812  
§  
§ Examiner: Lynne Ann Gurley  
§  
§ Atty. Docket: 2003-0659.00/US  
§  
§  
§  
§  
§

Commissioner for Patents  
PO Box 1450  
Alexandria, VA 22313-1450

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Signature

**RESPONSE TO THE OFFICE ACTION OF JANUARY 22, 2004**

Please enter the following in response to the Examiner's office action mailed January 22, 2004 as paper no. 1203.